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Docket No. 07977-082003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of	)
Shunpei YAMAZAKI et al.	)
Serial No. 09/917, 095	) Art Unit: 2829
Filed: July 26, 2001	) Examiner: PIET, EVANT
For: PLASMA CVD METHOD	)

TERMINAL DISCLAIMER

Honorable Assistant Commissioner for Patents  
Washington, D. C. 20231

Sir:

I, Dr. Shunpei Yamazaki, having a place of business at Semiconductor Energy Laboratory Co., Ltd., 398, Hase, Atsugi-shi, Kanagawa-ken 243-0036 Japan, state that I am authorized to sign on behalf of the assignee of this invention and that the Assignment referred to below has been reviewed and certify that, to the best of my knowledge and belief, the entire right, title and interest in the above-identified application is in the name of Semiconductor Energy Laboratory Co., Ltd. by virtue of an Assignment recorded in the U.S. Patent and Trademark Office at Reel 03465, Frame 0721-3.

Semiconductor Energy Laboratory Co., Ltd. hereby disclaims, except as provided below, the terminal part of the statutory term of any patent granted on the instant application, which would extend beyond the expiration date of the full statutory term defined in 35 U.S.C. 154 to 156 and 173, as presently shortened by any terminal disclaimer, of prior Patent No. 6,281,147.

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